

FIG. I

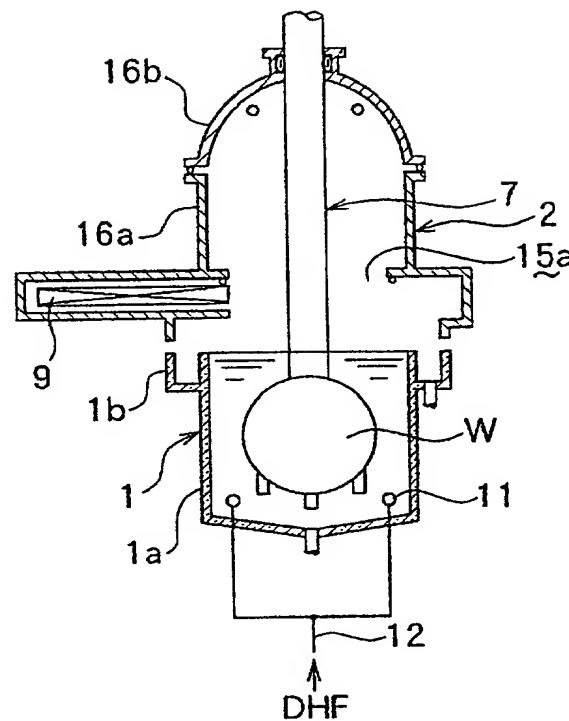


FIG. 2

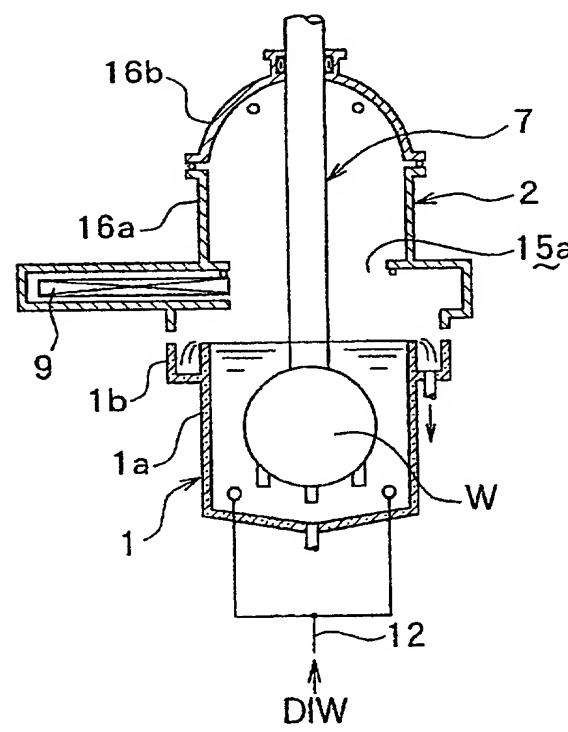


FIG. 3

Title: Method And Apparatus Of Processing Surface Of Substrate

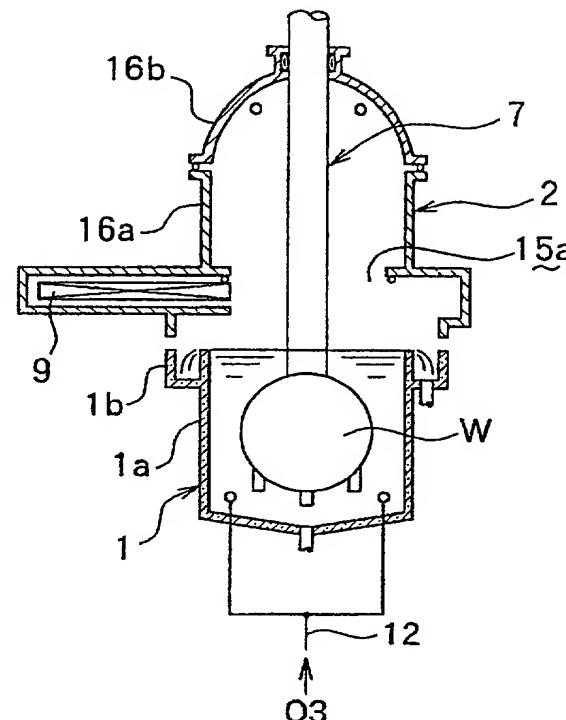
Inventor: Takayuki TOSHIMA et al.

Application No.: Not yet assigned

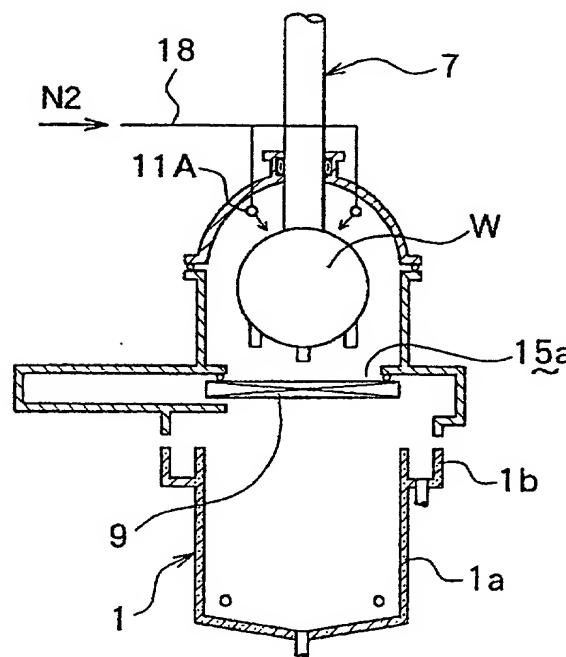
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F I G. 4



F I G. 5

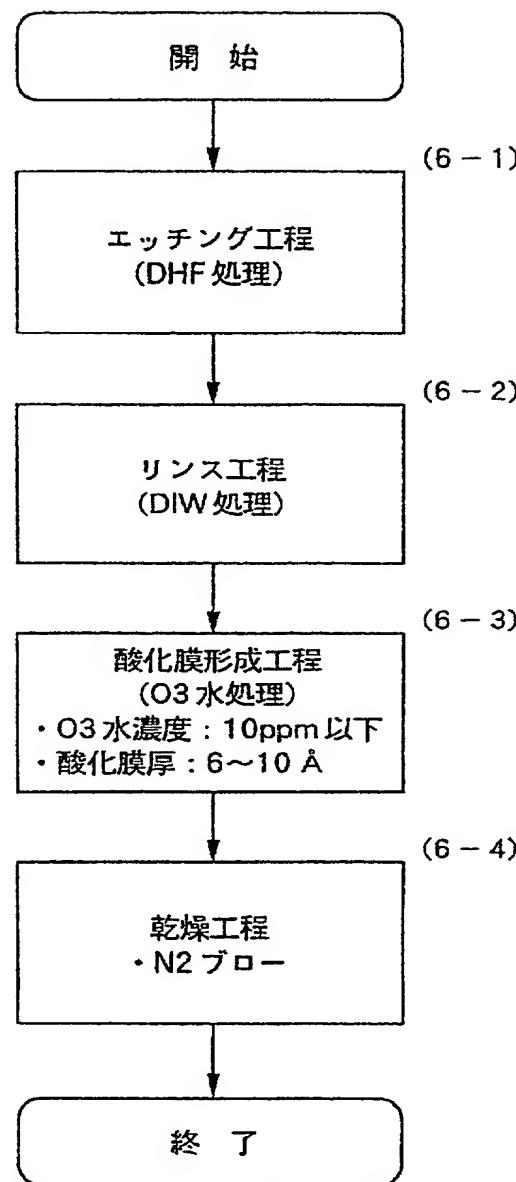


FIG. 6

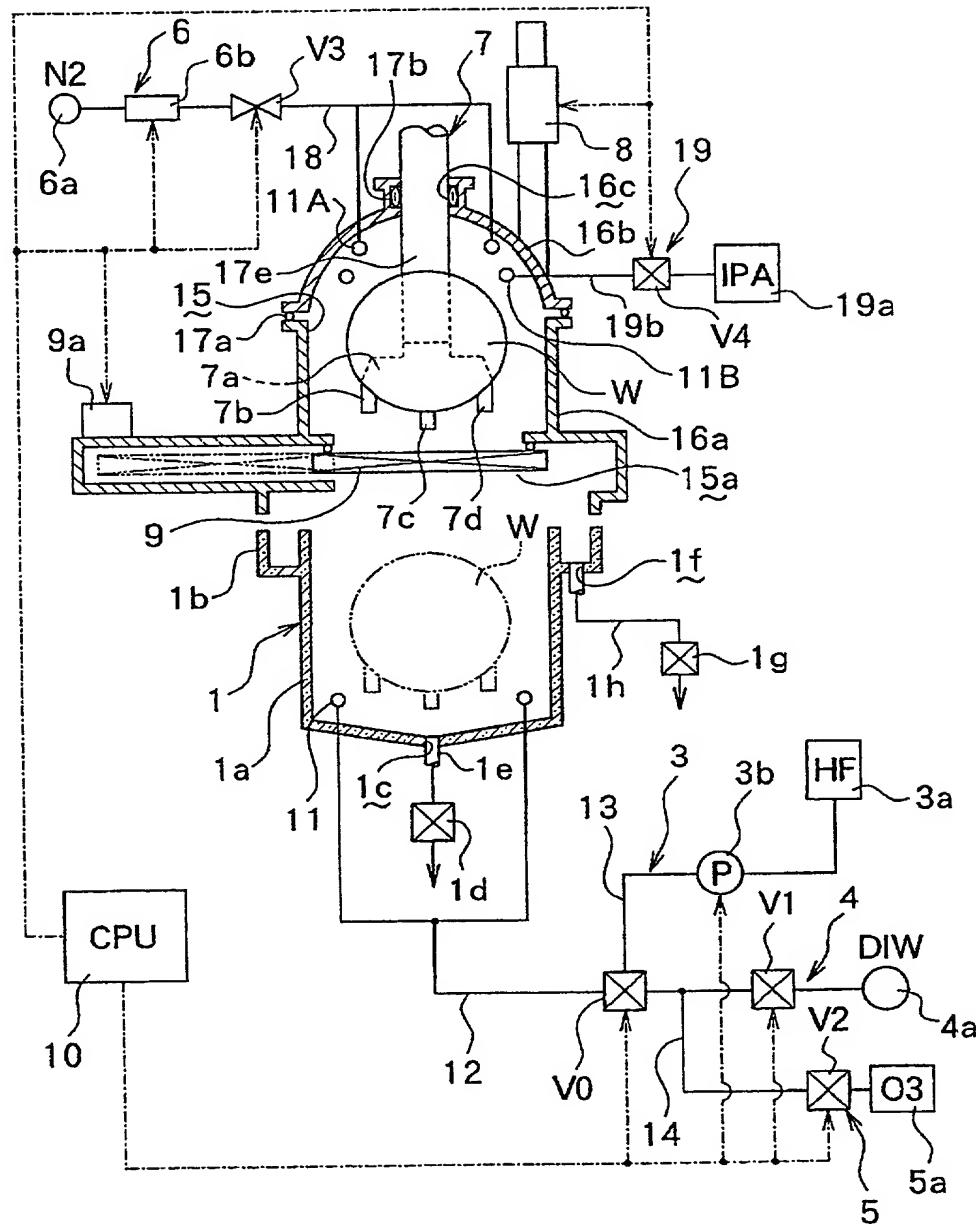


FIG. 7

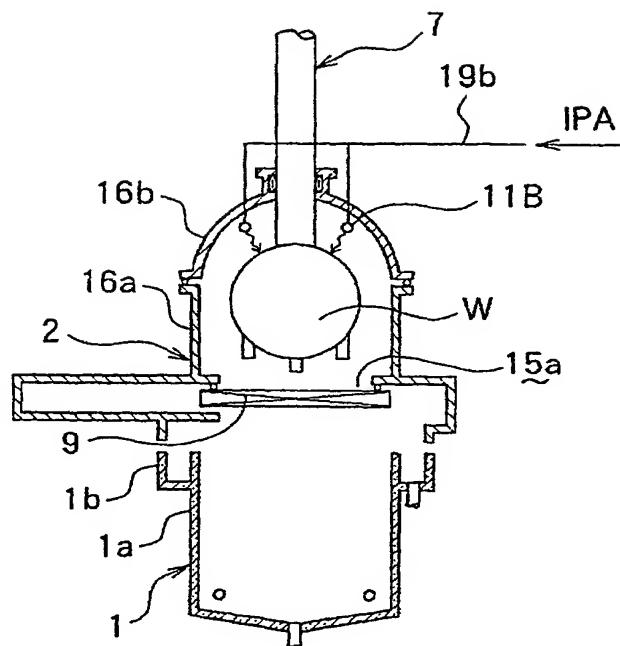


FIG. 8

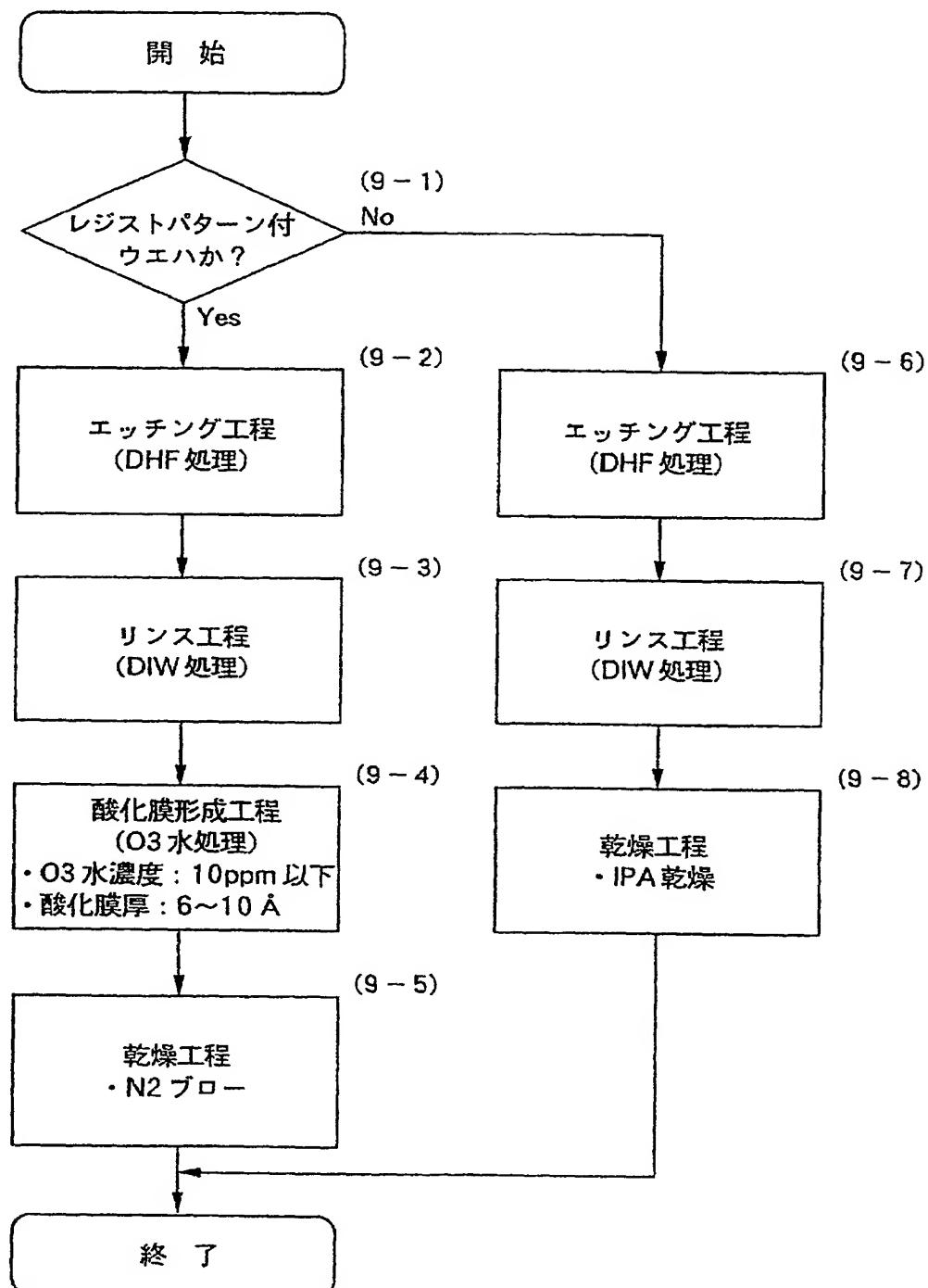


FIG. 9

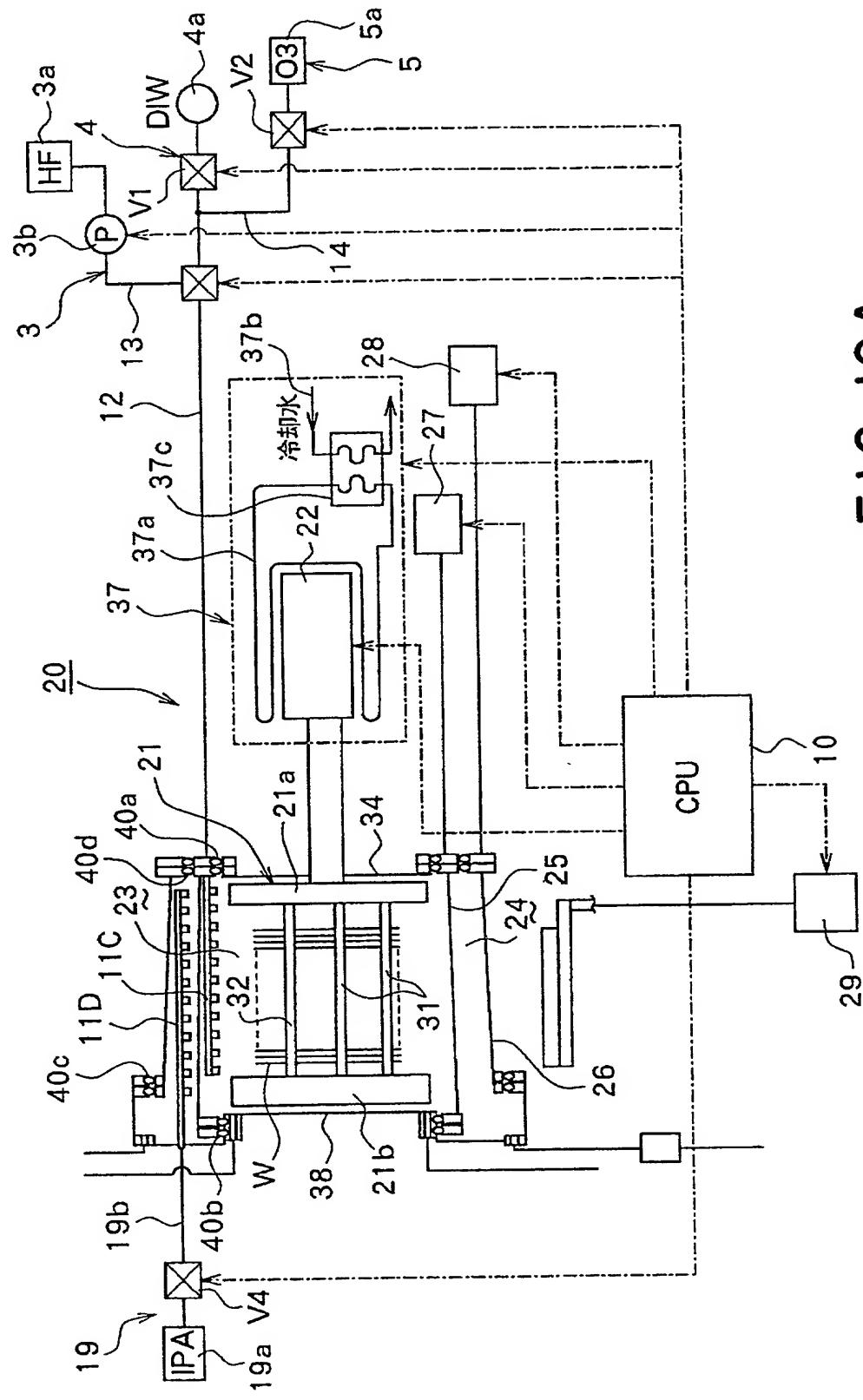


FIG. 10A

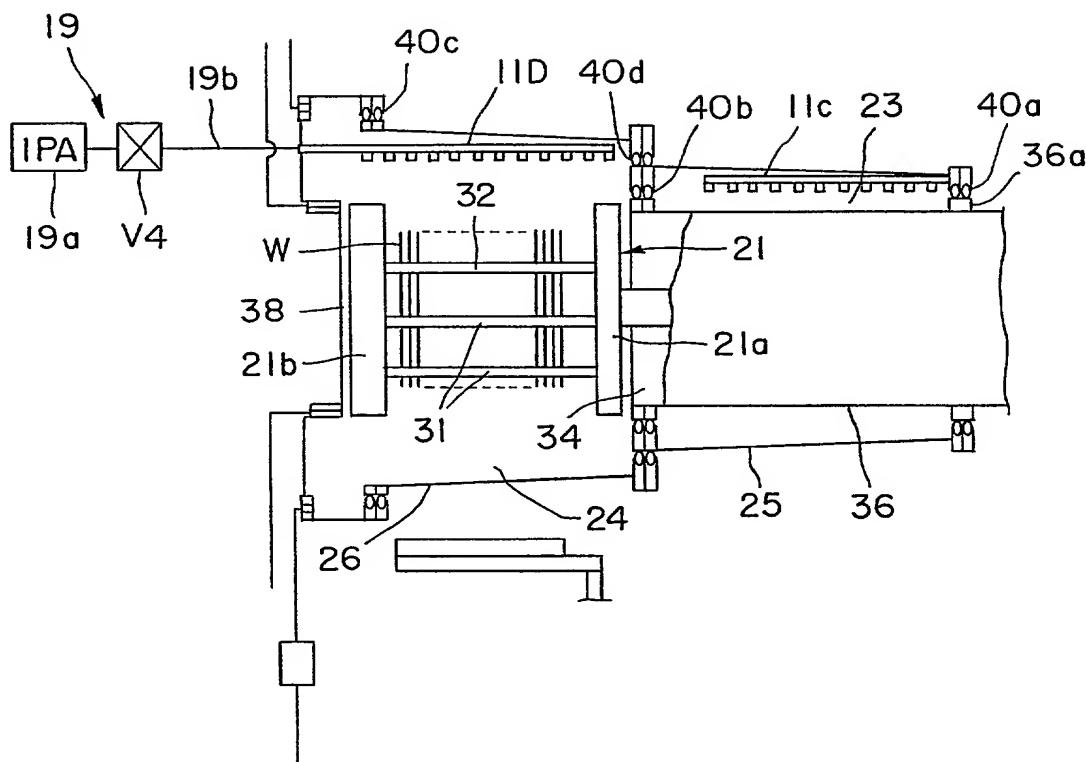


FIG. 10B

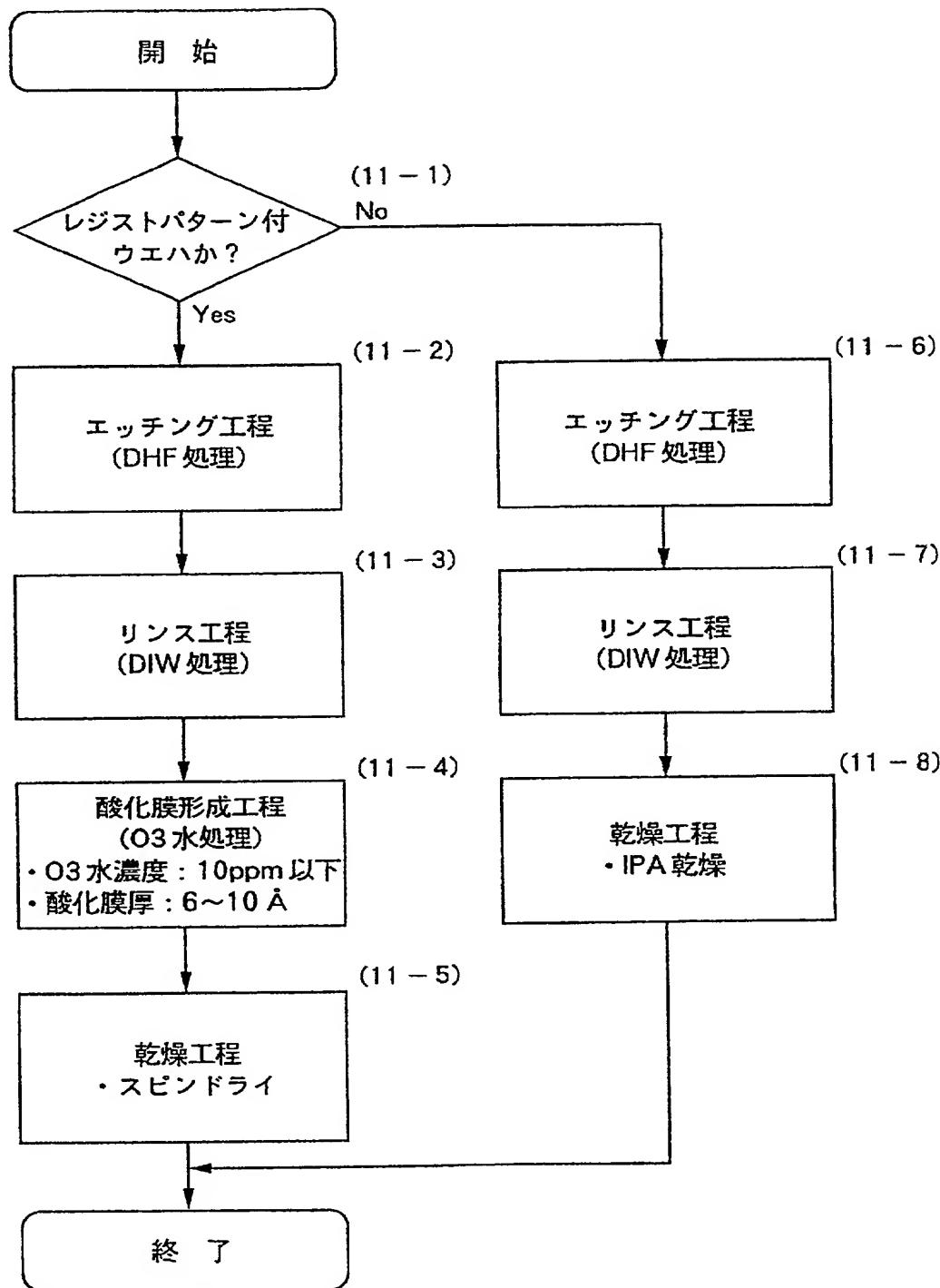
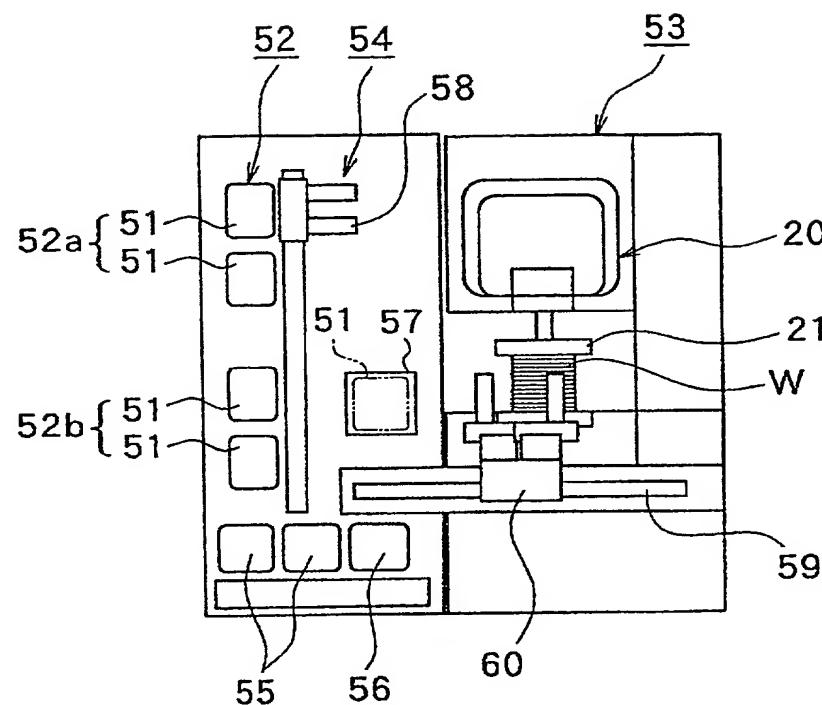


FIG. 11



F I G. 12

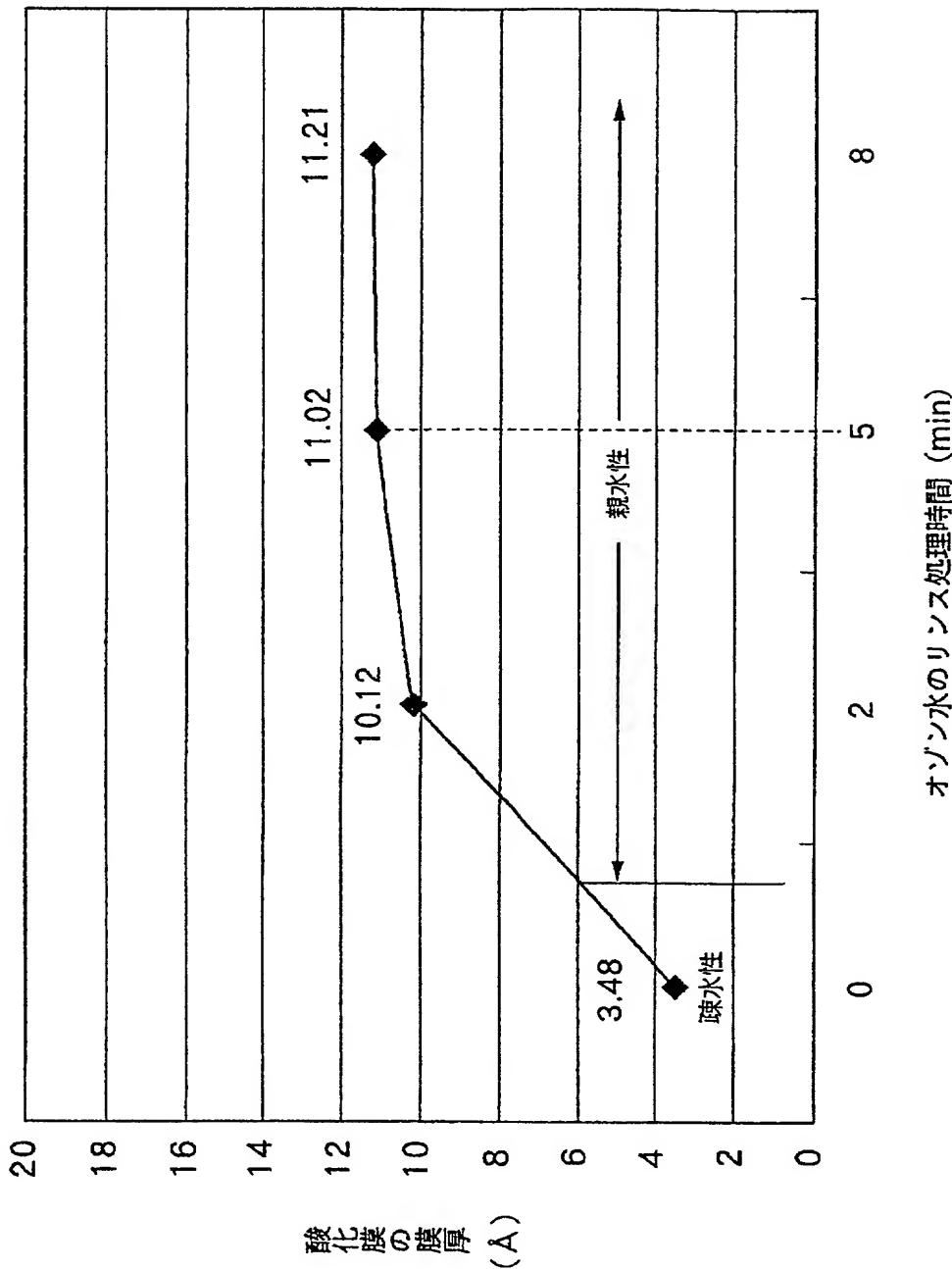


FIG. 13

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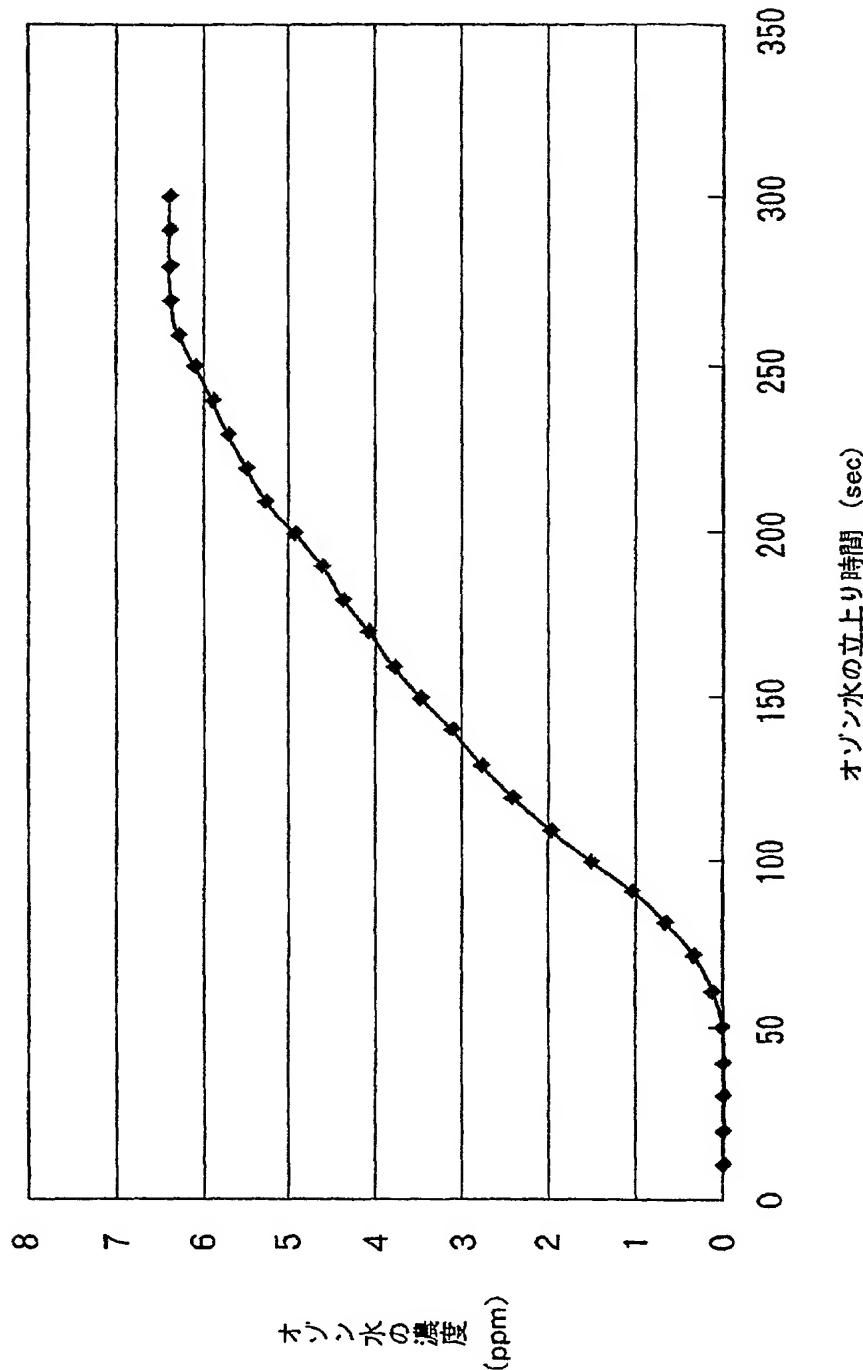


FIG. 14